SSDM 2003 Condensed Program

## Tuesday, September 16

EMINENCE HALI	

Room A	Room B	Room C	Room	D	Room E	Room F	Room G
14:00-15:50 A-1: Advanced Silicon Devices and Device Physics -Gate Stack Technologies- (5 papers)	14:00-16:00 B-1: Non-Volatile Memory Technologies -Non-Volatile Memory I- (5 papers)	14:00-15:50 C-1: Silicon Process / Materials Technologies -High-k Gate Dielectric I- (5 papers)	14:00-16:00 D-1: New Characterization -Oxide Reliability Characterization- (6 papers)	Materials and and Surface	14:00-16:00 E-1: Quantum Nanostructure Devices and Physics -Fabrication and Micromechanics- (7 papers)	14:00-16:00 F-1: Compound Semiconductor Materials and Devices -III-V and Nitride Electron Devices- (7 papers)	14:00-15:50 G-1: Advanced Silicon Circuits and Systems -Advanced CMOS Circuits and Systems- (5 papers)
16:15-18:15 A-2: Advanced Silicon Devices and Device Physics -Advanced CMOS Technology I- (6 papers)	16:15-17:35 B-2: Non-Volatile Memory Technologies -Non-Volatile Memory II- (4 papers)	16:15-17:55 C-2: Silicon Process / Materials Technologies -High-k Gate Dielectric II- (5 papers)	16:15-18:15 D-2: New Characterization -Low k and Characterization- (6 papers)	Materials and Silicide	16:15-18:00 E-2: Quantum Nanostructure Devices and Physics -Nanostructured Optical Devices- (6 papers)	16:15-18:00 F-2: Compound Semiconductor Materials and Devices -Nitride Electron Devices- (6 papers)	16:15-17:45 G-2: Advanced Silicon Circuits and Systems -Collaboration of Circuits and Devices- (4 papers)

18:30-20:30 Banquet, Eminence Hall

Wednesday, September 17

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Room A	Room B	Room C	Room	D	Room E	Room F	Room G
9:00-10:30 A-3: Advanced Silicon Devices and Device Physics -High-k Technology I- (4 papers)	9:00-10:20 B-3: Non-Volatile Memory Technologies -Non-Volatile Memory III- (3 papers)	9:00-10:30 C-3: Silicon Process / Materials Technologies -Memory Technology- (4 papers)	9:00-10:30 D-3: Silicon- Technologies -SOI Novel (4 papers)	on-Insulator Devices-	9:00-10:15 E-3: Quantum Nanostructure Devices and Physics -Characterization and Nanoprobing- (5 papers)	9:00-10:15 F-3: Compound Semiconductor Materials and Devices -Novel Compound Semiconductors Devices- (3 papers)	9:00-10:30 G-3: Advanced Silicon Circuits and Systems -Circuit Technologies for Emerging Technologies- (4 papers)
10:45-12:00 A-4: Optoelectronic Devices and Photonic Crystal Devices -VCSELs and Visible Lasers- (4 papers)	10:45-12:05 B-4: Non-Volatile Memory Technologies -Non-Volatile Memory IV- (4 papers)	10:45-12:05 C-4: Silicon Process / Materials Technologies -DRAM- (4 papers)	10:45-12:05 D-4: Silicon- Technologies -SOI Device (4 papers)	on-Insulator Physics-	10:45-12:15 E-4: Quantum Nanostructure Devices and Physics -Spin-related Phenomena- (5 papers)	10:45-12:15 F-4: Compound Semiconductor Materials and Devices -Optical Devices- (5 papers)	10:45-11:45 G-4: System-Level Integration and Packaging Technologies -System-Level Integration and Packaging Technologies I- (3 papers)
13:00-15:00 Poster Session (OHGI)	)						
15:15-16:45 A-5: Optoelectronic Devices and Photonic Crystal Devices -Optoelectronic Integrated Devices- (5 papers)	15:15-16:30 B-5: Organic Semiconductor Devices and Materials -Preparation and Characterization- (5 papers)	15:15-16:45 C-5: Silicon Process / Materials Technologies -Interconnect- (4 papers)	15:15-16:45 D-5: Silicon- Technologies -Fin FET (4 papers)	on-Insulator Technologies-	15:15-16:30 E-5: Quantum Nanostructure Devices and Physics -Single Electron Transport- (4 papers)	15:15-16:45 F-5: Micro-Nano Electromechanical Devices for Bio- and Chemical Applications -Micro-Nano Electro Mechanical Devices for Bio-and Chemical Applications I- (5 papers)	15:15-16:45 G-5: System-Level Integration and Packaging Technologies -System-Level Integration and Packaging Technologies II- (4 papers)
17:00-18:15 A-6: Optoelectronic Devices and Photonic Crystal Devices -Lasers for Optical Communication- (4 papers)	17:00-17:40 B-6: Non-Volatile Memory Technologies -Non-Volatile Memory V- (2 papers)	17:00-18:20 C-6: Silicon Process / Materials Technologies -Interconnect- (4 papers)	17:00-18:30 D-6: New Characterization -Si/SiGe Materials- (4 papers)	Materials and Devices and	17:00-18:30 E-6: Novel Devices, Physics, and Fabrication -Nanoprocess and Nanodevices- (5 papers)	17:00-18:00 F-6: Micro-Nano Electromechanical Devices for Bio- and Chemical Applications -Micro-Nano Electro Mechanical Devices for Bio-and Chemical Applications II- (3 papers)	17:00-18:15 G-6: System-Level Integration and Packaging Technologies -System-Level Integration and Packaging Technologies III- (4 papers)

18:45-20:45 Rump Session

Room A "Can channel material/structure engineering become a guiding principle for future CMOS device technology?"
Room B "What paradigm can nanoelectronic devices bring about?"

Thursday, September 18

Thursday, September 10							
Room A	Room B	Room C	Room	D	Room E	Room F	Room G
9:00-10:30	9:00-10:20	9:15-10:30	9:20-10:30		9:30-10:30	9:00-10:30	9:00-10:30
A-7: Advanced Silicon Devices	B-7: Silicon Process / Materials	C-7: Organic Semiconductor	D-7: New	Materials and	E-7: Novel Devices, Physics, and	F-7: Optoelectronic Devices and	G-7: SiGe/III-V/III-N Devices and
and Device Physics	Technologies	Devices and Materials	Characterization		Fabrication	Photonic Crystal Devices	Circuits for Wireless and Optical
-High-k Technology II-	-Metal Gate, Gate Oxde-	-Organic Thin Film Transistor-	-Carbon	Nanotube	-Novel Materials and Devices-	-Photonic Crystal Devices I-	Communications
(4 papers)	(4 papers)	(4 papers)	Devices and	Materials-	(4 papers)	(5 papers)	-III-V Devices & Circuits-
			(3 papers)				(5 papers)
10:45-12:05	10:45-12:05	10:45-12:00	10:45-11:25		10:45-12:00	10:45-11:45	10:45-11:45
A-8: Advanced Silicon Devices	B-8: Silicon Process / Materials	C-8: Organic Semiconductor	D-8: New	Materials and	E-8: Novel Devices, Physics, and	F-8: Optoelectronic Devices and	G-8: SiGe/III-V/III-N Devices and
and Device Physics	Technologies	Devices and Materials	Characterization		Fabrication	Photonic Crystal Devices	Circuits for Wireless and Optical
-Advanced CMOS Technology II-	-Si Process-	-Organic Optics-	-High-k	Dielectrics I-	-Carbon Nanotubess-	-Photonic Crystal Devices II-	Communications
(4 papers)	(4 papers)	(5 papers)	(2 papers)		(4 papers)	(3 papers)	-SiGe Technologies- (3 papers)
13:30-14:50	13:30-14:40	13:30-14:45	13:30-14:30		13:30-14:30	13:30-14:45	13:30-14:45
A-9: Advanced Silicon Devices	B-9: Silicon-on-Insulator	C-9: Organic Semiconductor	D-9: New	Materials and	E-9: Novel Devices, Physics, and	F-9: Optoelectronic Devices and	G-9: SiGe/III-V/III-N Devices and
and Device Physics	Technologies	Devices and Materials	Characterization		Fabrication	Photonic Crystal Devices	Circuits for Wireless and Optical
-Electron Mobility Characteristics-	-SOI Low Power Applications-	-Molecular Devices and Materials-	-High-k	Dielectrics II-	-Si Nanowire and Dots-	-Ultrafast Photonic Devices-	Communications
(4 papers)	(3 papers)	(4 papers)	(3 papers)		(4 papers)	(4 papers)	-GaN Devices- (4 papers)
15:00-16:00	15:00-16:30	15:00-16:00	15:00-16:20		15:00-16:15	15:00-16:00	15:00-16:00
A-10: Advanced Silicon Devices	B-10: Silicon-on-Insulator	C-10: Organic Semiconductor	D-10: New	Materials and	E-10: Novel Devices, Physics, and	F-10: Optoelectronic Devices and	G-10: SiGe/III-V/III-N Devices
and Device Physics	Technologies	Devices and Materials	Characterization		Fabrication	Photonic Crystal Devices	and Circuits for Wireless and
-Poly-Si Device and Sensor-	-SOI CMOS Technologies-	-Electroluminescent Devices and	-High-k	DielectricsIII-	-Quantum Computing Devices-	-New Photonic Materials-	Optical Communications
(3 papers)	(4 papers)	Materials-	(4 papers)		(4 papers)	(4 papers)	-High Voltage Devices-
		(4 papers)					(3 papers)